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Patent

OCT 28 2004

Customer No.: 31561  
Docket No. 12398-US-PA  
Application No.: 10/707,632

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of

Applicant : Lin et al.

Application No. : 10/707,632

Filed : 2003/12/26

For : STRUCTURE APPLIED TO A PHOTOLITHOGRAPHIC  
PROCESS AND METHOD FOR FABRICATING A  
SEMICONDUCTOR DEVICE

Art Unit : 2813

Examiner : PHAM, THANHHA S

**TRANSMITTAL LETTER**

002-1-703-872-9306

(Via fax: 7 pages)

Assistant Commissioner for Patents  
Arlington, Virginia 22202

Dear Sir,

In response to the Office Action dated September 28, 2004, please find the *Response to Restriction Requirement*, in 6 pages, in response to paper No. 09262004.

I believe that no fee is incurred. However, the Commissioner is authorized to charge any fees required in connection with the filing of this paper to account No. 50-2620 (Order No.: 12398-US-PA)

Thank you for your assistance in the subject matter. If you have any questions, please feel free to contact me.

Respectfully Submitted,  
JIANQ CHYUN Intellectual Property Office

Date: Oct. 28, 2004

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Application No.: 10/707,632  
Docket No.: 12398-US-PA

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

|                               |   |                            |
|-------------------------------|---|----------------------------|
| In Re Application of:         | ) |                            |
| Shun-Li Lin et al.            | ) |                            |
|                               | ) | Examiner : PHAM, THANHHA S |
|                               | ) |                            |
| Serial No. : 10/707,632       | ) | Art Unit : 2813            |
|                               | ) |                            |
| Filed : 12/26/2003            | ) |                            |
|                               | ) | Docket No. : 12398-US-PA   |
| For: STRUCTURE APPLIED TO A   | ) |                            |
| PHOTOLITHOGRAPHIC PROCESS AND | ) |                            |
| METHOD FOR FABRICATING        | ) |                            |
| A SEMICONDUCTOR DEVICE        | ) |                            |

No fee is believed to be due. However, the Commissioner is authorized to charge any fees required in connection with the filing of this paper to account No. 50-2620 (Order No. 12398-US-PA).

RESPONSE TO RESTRICTION REQUIREMENT

U.S. Patent and Trademark Office  
Commissioner for Patents  
220 20th Street South  
Customer Window, Mail Stop Amendment  
Crystal Plaza Two, Lobby, Room 1B03  
Arlington, Virginia 22202

Dear Sir:

In response to the Restriction Requirement mailed on September 28, 2004 regarding to the above-identified application, Applicant elects Group IIa, claims 7-10, for further examination on merits. Please cancel Groups I, claim 1-6 and IIb, claims 11-13 without prejudice or disclaimer.

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**Further, prior to the examination on merits, please amend the above-captioned application as follows:**